

Invention: WAFER PROBE STATION FOR LOW-CURRENT MEASUREMENTS

Filed: Herewith

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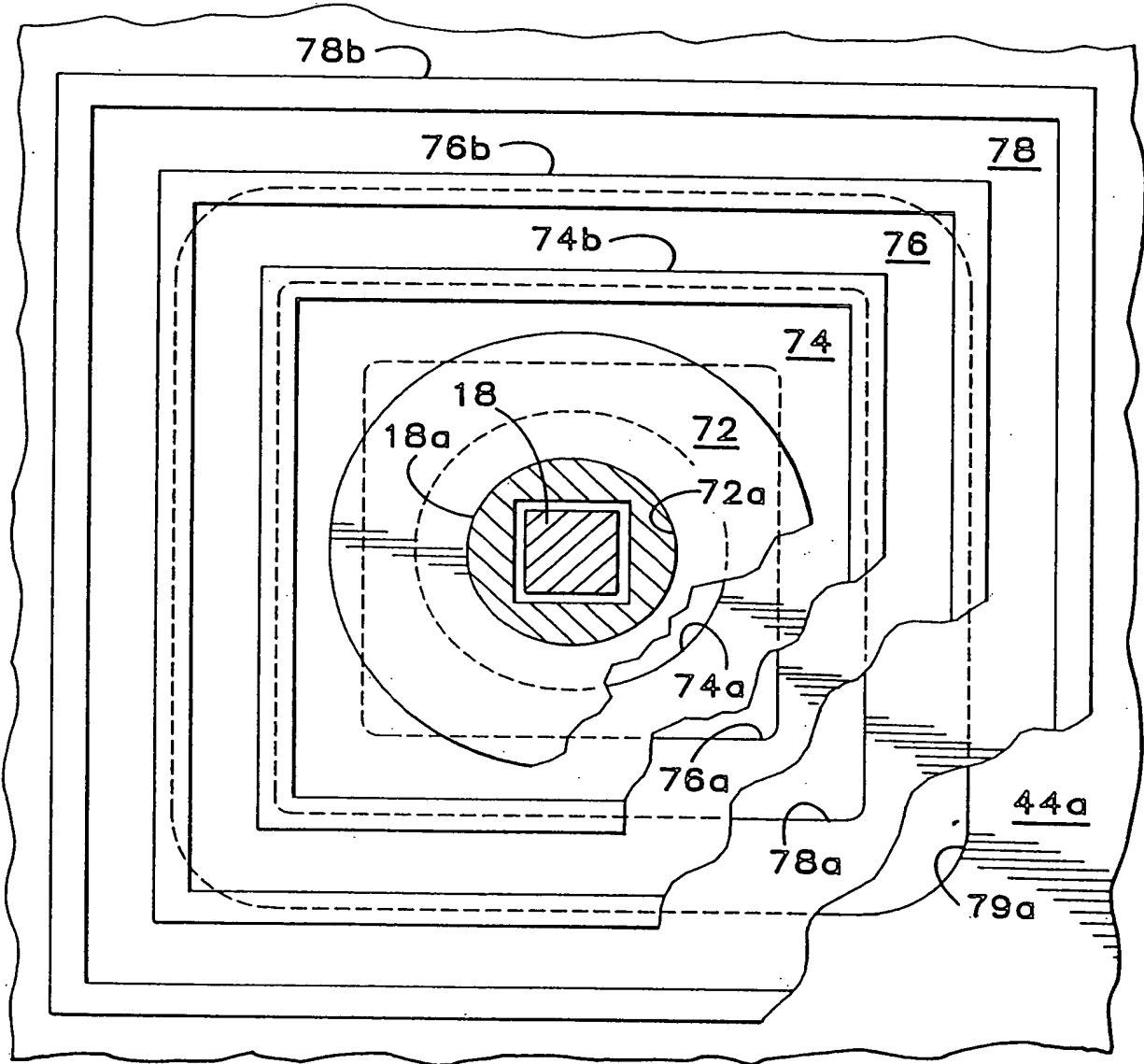
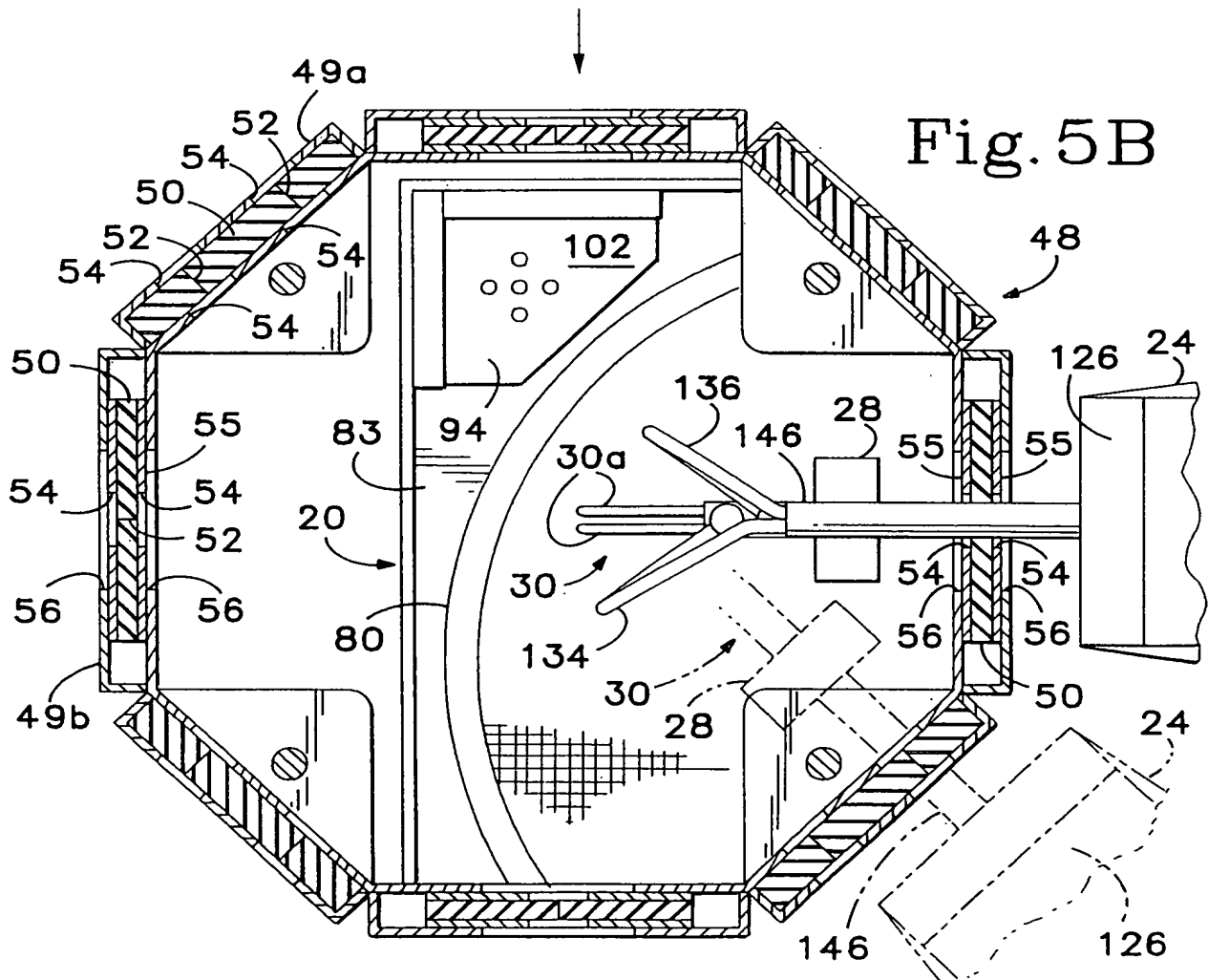
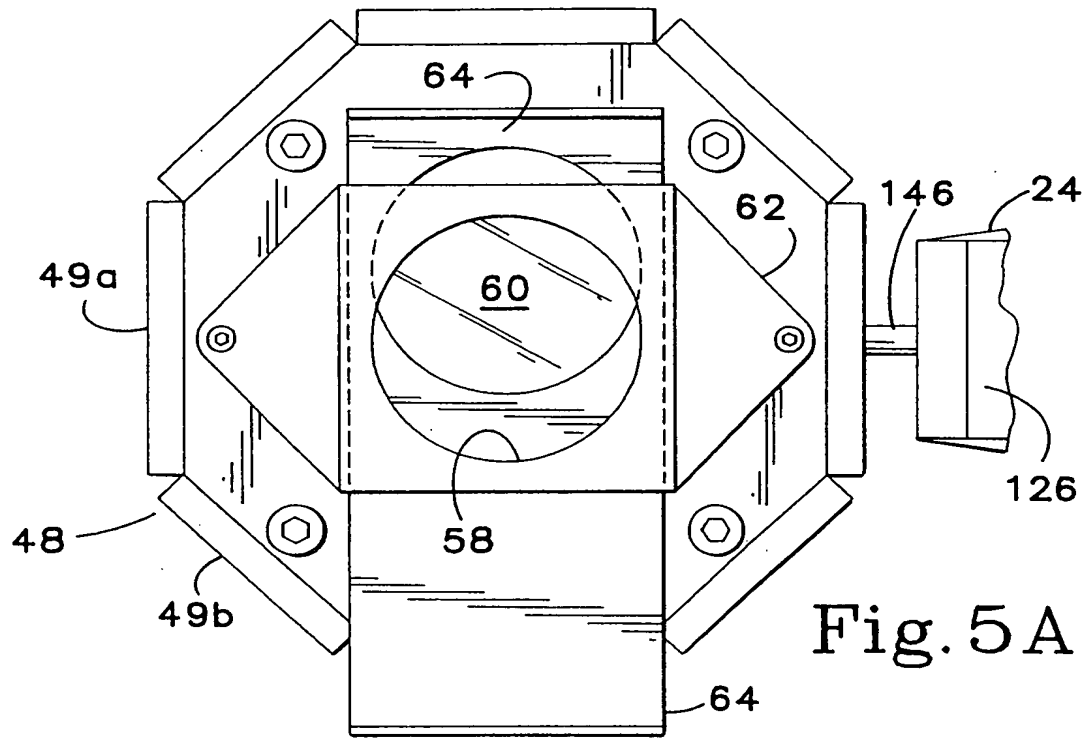
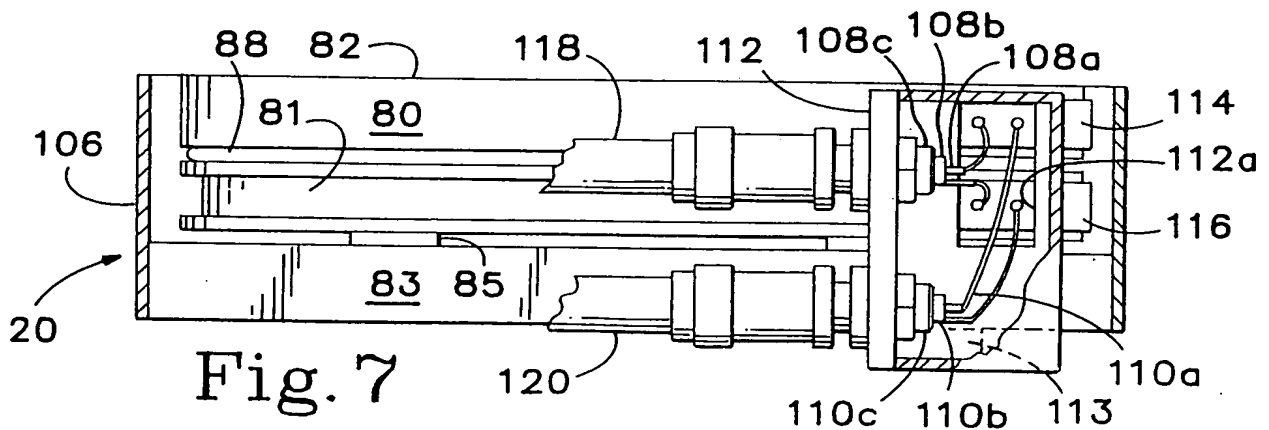
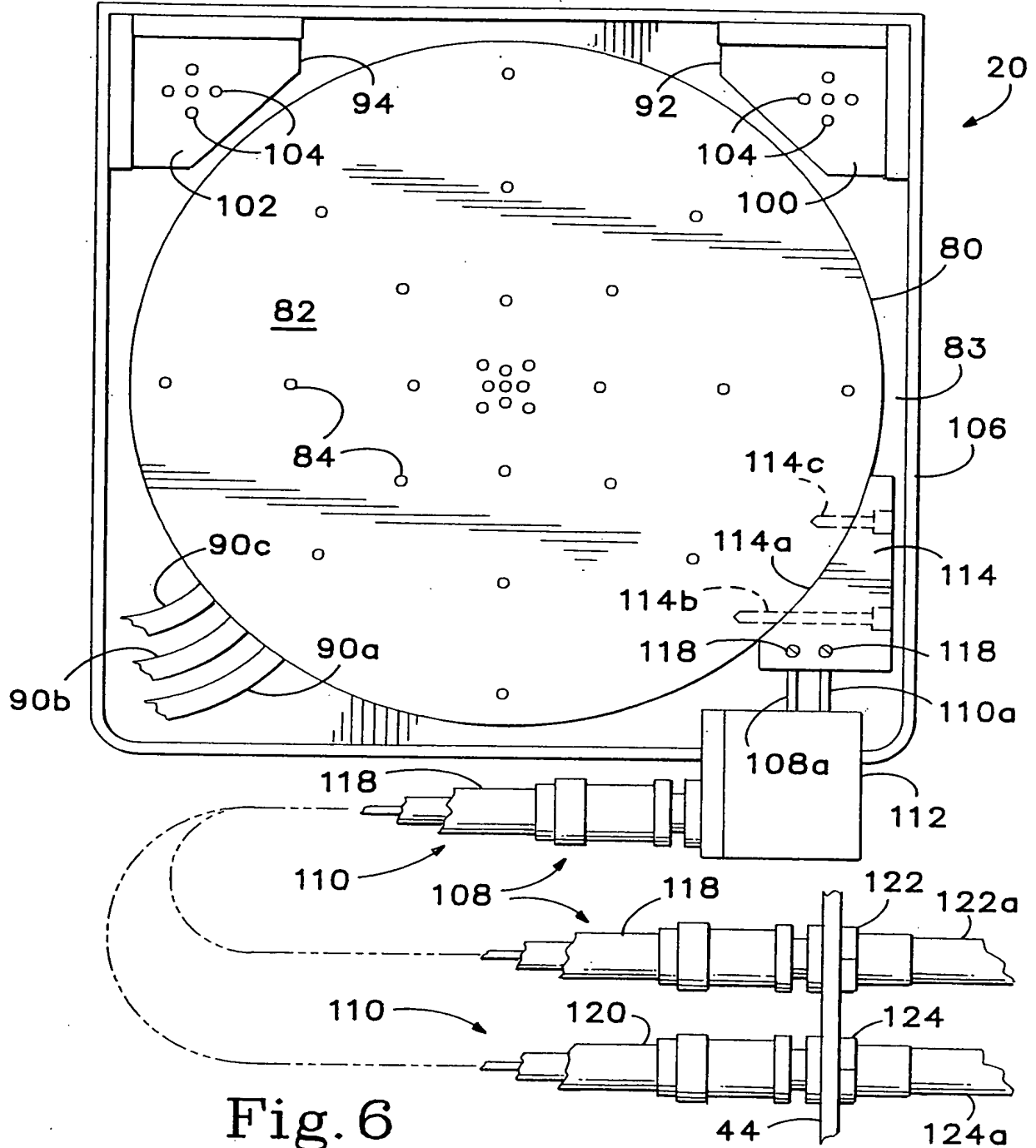
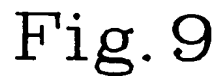
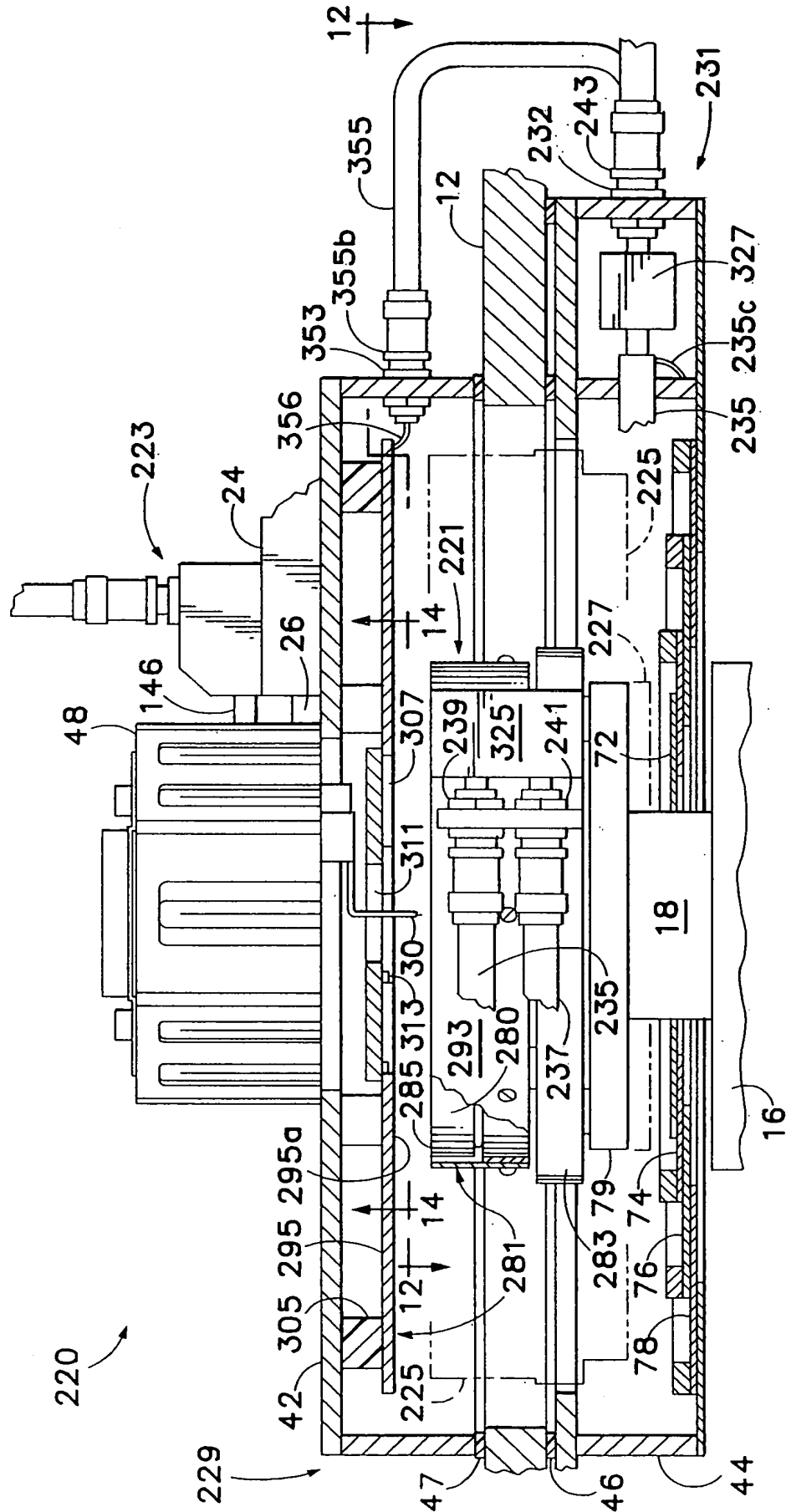


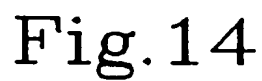
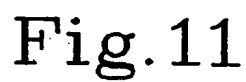
Fig. 4











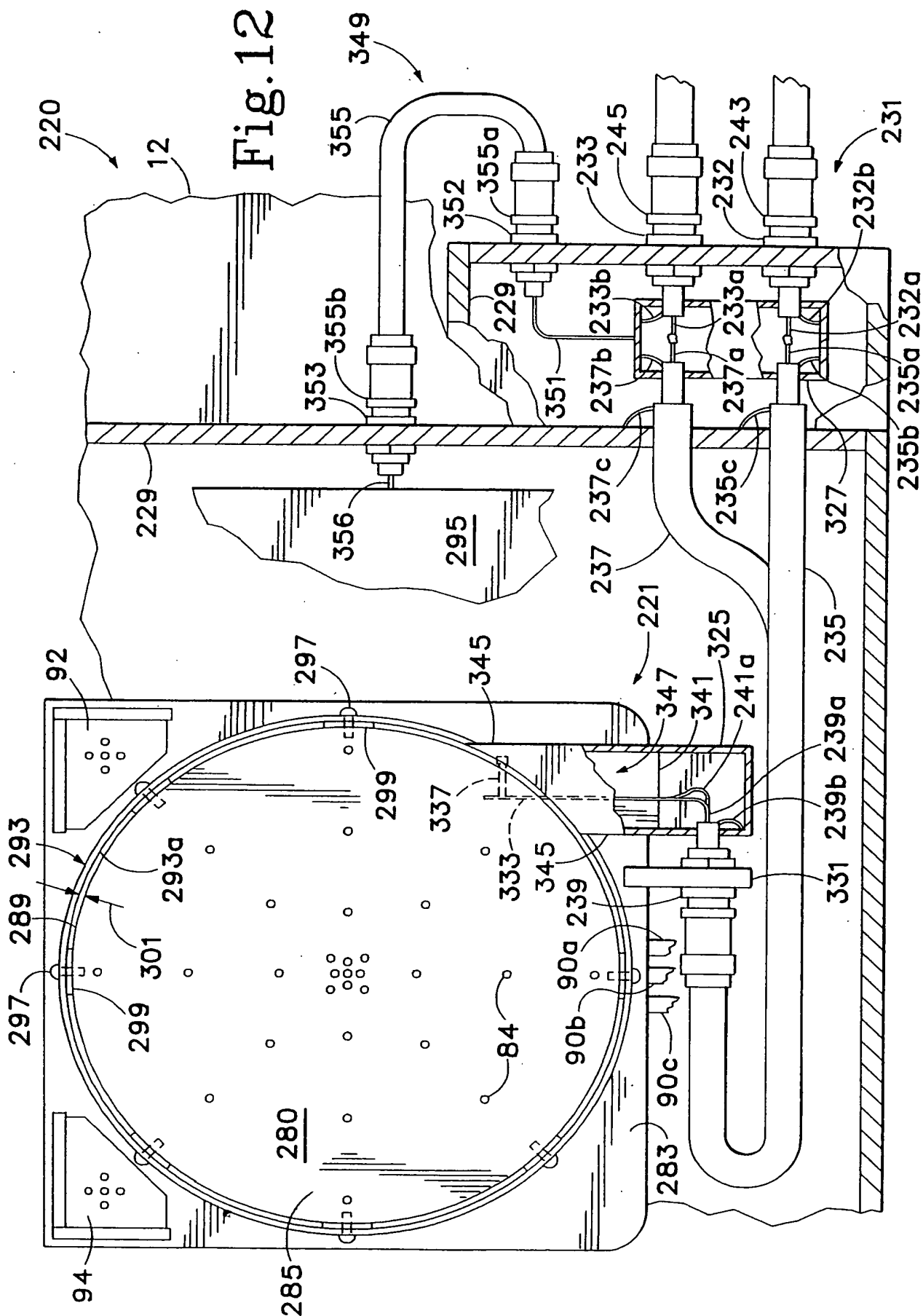


Fig. 13

Fig. 13 is a cross-sectional view of a device 220. The device includes a curved, dome-like component 280 with a grid of small circles on its surface. A central shaft 221 passes through the center of the dome. A component 317 is located at the base of the dome, with a sub-component 317a. A component 323 is also shown near the base. A component 319 is located on the side of the dome. A component 283 is located on the side of the dome. A component 315 is located on the side of the dome. A component 321 is located on the side of the dome. A component 325 is located on the side of the dome. A component 70 is located at the base of the dome. A component 229 is located on the side of the dome. A component 231 is located on the side of the dome. A component 232 is located on the side of the dome. A component 243 is located on the side of the dome. A component 245 is located on the side of the dome. A component 233 is located on the side of the dome. A component 355a is located on the side of the dome. A component 355b is located on the side of the dome. A component 353 is located on the side of the dome. A component 352 is located on the side of the dome. A component 355 is located on the side of the dome.

